

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

METHODS OF THINNING A SILICON WAFER USING HF AND
OZONE

Application Number : 10/631376
Confirmation Number: 2135
First Named Applicant: Eric Bergman
Attorney Docket Number: 54008.8033.US00
Art Unit: 1746
Examiner: Zeinab El-Arini
Search string: (6162734 or 6806205).pn



US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

| init | Cite.No. | Patent No. | Date | Patentee | Kind | Class | Subclass |
|------|----------|------------|------------|----------------|------|-------|----------|
| | 1 | 6162734 | 1995-10-12 | Bergman et al. | | | |
| | 2 | 6806205 | 2000-12-29 | Jang et al. | B2 | | |

Signature

| Examiner Name | Date |
|---------------|------|
| | |